



Silicon Detectors for the sLHC an Overview of Recent RD50 Results

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on behalf of the RD50 Collaboration



Overview



- Radiation environment and requirements for silicon sensors at SLHC
- Introduction of the RD50 Collaboration
- Some examples from the five research lines within RD50
 - This report cannot be complete!
 - See coming Status Report for more details
- Recommendations for SLHC

http://cern.ch/rd50/

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Radiation Environment



- Pixel dominated by charged hadron radiation (up to 2.5 · 10¹⁶ cm⁻²).
- From about 40cm on neutron radiation is dominating (~4·10¹⁴ cm⁻²).
- Ratio of neutron fraction vs. charged hadron fraction is changing with radius.
- Have to investigate damage due to neutral and charged particles and combinations.



Requirements at SLHC



- Much higher radiation tolerance required at SLHC
- Standard FZ material and operation not sufficient any more
- Need new sensor materials and/or technologies
- To find a suitable sensor technology for SLHC is the aim of RD50

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The RD50 Collaboration

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41 European and Asian institutes

Belarus (Minsk), Belgium (Louvain), Czech Republic
(Prague (3x)), Finland (Helsinki), Laappeenranta), Germany
(Dortmund, Erfurt, Freiburg, Hamburg, Karlsruhe, Munich),
Italy (Bari, Bologna, Florence, Padova, Perugia, Pisa, Torino,
Trento), Lithuania (Vilnius), Netherlands (NIKHEF), Norway
(Oslo (2x)), Poland (Warsaw(2x)), Romania (Bucharest (2x)),
Russia (Moscow, St.Petersburg), Slovenia (Ljubljana), Spain
(Barcelona, Valencia), Switzerland (CERN, PSI), Ukraine
(Kiev), United Kingdom (Exeter, Glasgow, Lancaster,





8 North-American institutes

Canada (Montreal), USA (BNL, Fermilab, New Mexico, Purdue, Rochester, Santa Cruz, Syracuse)

1 Middle East institute

Israel (Tel Aviv)

Detailed member list: http://cern.ch/rd50

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Defect / Material Characterization Bengt Svensson (Oslo University)	Defect Engineering Eckhart Fretwurst (Hamburg University)	Pad Detector Characterization <i>G. Kramberger</i> (Ljubljana)	New Structures <i>R. Bates</i> (Glasgow University)	Full Detector Systems Gianluigi Casse (Liverpool University)
Characterization of microscopic properties of standard-, defect engineered and new materials pre- and post-irradiation WODEAN project (G. Lindstroem)	Development and testing of defect engineered silicon: - Epitaxial Silicon - High res. CZ, MCZ - Other impurities H, N, Ge, - Thermal donors - Pre-irradiation	 Test structure characterization IV, CV, CCE NIEL Device modeling Operational conditions Common irrad. Standardisation of macroscopic measurements (A.Chilingarov) 	 •3D detectors •Thin detectors •Cost effective solutions •3D (M. Boscardin) •Semi 3D (Z.Li) 	 LHC-like tests Links to HEP Links to R&D of electronics Comparison: pad-mini-full detectors Comparison of detectors different producers (Eremin) Pixel group (D. Bortoletto, T. Rohe)

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Long Term Annealing

- The defect centres H(116K), H(140K), H(152K) are hole traps with acceptor like levels in the lower band gap (neg. space charge)
- They are not generated by gamma irradiation, thus cluster related
- Concentrations are increasing with annealing time
 - \rightarrow contribute to long term/reverse annealing
- N_{eff} can be calculated from measured defect concentrations with TSC including BD and E(30K) defects
- Comparison with N_{eff} from CVmeasurements strikingly good

[I. Pintilie, E. Fretwurst, and G. Lindström, APL 92, 024101 2008]



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Defect Overview

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Thermal Donors





Tailoring of N_{eff} in **p-type MCz** silicon by creation of thermal donors after heat treatment at 450°C

Radiation hardness is being tested...

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Charge Multiplication

- CCE increases over expectation for very high fluence
- CCE > 100% for high bias voltage
- There is charge multiplication ! (Avalanche effect ?)



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Bias depending V_{fd}

- It was observed that full depletion voltage of irradiated FZ devices increases with time when bias is applied and goes back to previous value without bias
- This effect is seen in MCz and EPI material as well
- Introduction rate $g_b \sim 0.004 \text{ cm}^{-1} (g_s(FZ)=0.02 \text{ cm}^{-1})$
- Effect can reach level of stable damage in MCz and EPI for fast charged hadrons
- No significant increase in leakage current at V_{fd} observed $\frac{220}{200}$



0.01 80 0.008 1/C² [1/pF²] l_{leak} [μΑ] bias on (T = 20°C) 60 0.006 bias off (T = 20°C) bias on (T = 20°C) bias on (T = -8°C) 40 bias off (T = 20°C) 0.004 bias off (T= -8°C) bias on (T = -8°C) 0.002 v = 10 kHz at 20°C 20 bias off (T = -8°C) v = 3 kHz at -8°C 250 50 150 200 250 300 0 50 100 150 200 300 350 100 Cz samples irradiated with $24^{V_{\text{bias}}[V]}$ GeV/c protons to $3 \cdot 10^{14} n_{eq}$ /cm² before and after applying bias for 140h [G. Kramberger et al, "Effect of bias voltage on the space charge in irradiated silicon detectors", NIM A 600 p.555-559] 13 A. Dierlamm 08/06/09

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Cz36, $\Phi_{eq} = 3.1 \times 10^{14} \text{ p cm}^{-2}$

100

0

200

300

400

time o Th

500



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From STC to DDTC

- In 3D sensors the charge collecting electrodes reach as columns into the silicon bulk allowing a sidewards charge collection → short drift time (drift distance = pitch) by keeping a high number of generated charge carriers (silicon thickness ~300µm)
- Single Type Column (STC) sensors have a low field region between columns, which causes low CCE
- Double-sided Double Type Column (DDTC) design developed at CNM can cure this drawback





Real photo of diagonal cut

[G. Pellegrini, 2nd Trento Workshop on Advanced Silicon Radiation Detectors, Trento, 2006]

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DDTC

n+



CCE in STC



- Laser scan with small spot $\sim 5\mu m$
- Lower signal in-between the columns as expected from electric field
- CCE after irradiation with 25MeV protons to 9.10¹⁴ neq/cm² close to 100%



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[U. Parzefall et al.,"Silicon microstrip detectors in 3D technology for the sLHC", doi:10.1016/j.nima.2009.03.122]

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CCE in DDTC



- Device from FBK-IRST (Trento)
- Test-beam 2008 with 225GeV/c muons and APV25 read-out
- 2D-efficiency at S/N>10 (Q>2fC)
- Bias: 40V
- Overall efficiency: 97% with clustering and 93% with no clustering
- See also poster of G.-F. Dalla Betta after this session





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Thin Sensors



- Collected charge in heavily irradiated thin sensors is higher than in thick sensors at same bias voltage
- Reverse current is similar for the same charge !
- No beneficial effect of thin sensors on leakage current ?
- Further investigations ongoing...
- See also talk from G. Casse on Wednesday





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p-type FZ Silicon

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25 [T. Affolder, TIPP09] -Still sufficient signal (7000e-) in 20 p-type FZ strip sensors after Collected Charge (ke) $10^{16} n_{eq}^{2}/cm^{2}$ for 900V 15 ··▲-·· Neutrons (500 V –=– Neutrons (900 V) ---- Pions (500 V) Almost no annealing effect on 10 Pions (900 V) 26 MeV Protons (500 V) CCE -26 MeV Protons (900 V) · · · 24 GeV Protons (500 V) 5 — 24 GeV Protons (900 V) 24 GeV Protons-Cold (500 V) — 24 GeV Protons-Cold (900 V) Ω 10 100 Fluence $(10^{14} n_{eq} \text{ cm}^{-2})$ time (days at 20°C) 25 500100015002000 2500Signal(10³ electrons) 20 - 4 - 500V proton irradiated 18 800V proton irradiated 500V neutron irradiated $CCE(10^3 \text{ electrons})$ 16 6.8 x 10¹⁴ cm⁻² (proton - 800V) 800V neutron irradiated 14 1.6 x 10¹⁵cm⁻² (neutron - 600V) 12 102 x 10¹⁵cm⁻² (proton - 500 V) 4.7 x 10¹⁵ cm⁻² (proton - 700 V) [G.Casse, RD50 Workshop, June 2008] [Data: G.Casse et al., NIMA 568 (2006) 46 and RD50 Workshops] MMol 0 10 20 30 40 50 60 70 80 90 100 110 120 0 100 200 300 400 500 Fluence($10^{14} n_{eq}/cm^2$) time at 80°C[min] 20 A. Dierlamm 08/06/09

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Mixed Irradiations

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• Mixed irradiations performed with:

- [T.Affolder et al. 13th RD50 Workshop, Nov.2008]
- (a) 5x10¹⁴ neutrons (1 MeV equivalent fluence)
- (b) 5x10¹⁴ protons (1 MeV equivalent fluence)





Recommendations for SLHC RD50

• Outer Layers (R>20cm, F< $10^{15}n_{eq}/cm^2$)

- p-type silicon microstrip detectors show encouraging results
 - collected charge >10000e- (300 μ m) at 500V after F=10¹⁵ n_{eq}/cm²
 - no reverse annealing in CCE
- MCz could be a solution
 - n-MCz has improved performance in mixed fields due to compensation of n and p damage
- Innermost Layers (R<20cm, $F\sim 10^{16}n_{eq}/cm^2$)
 - active thickness reduced due to trapping
 - collect electrons (use n⁺-n or n⁺-p sensors)
 - thin planar silicon still an option
 - 3D detectors promising, but technology has to be optimized
 - \rightarrow intensive work going on